

Lecture 23 - The Si surface and the Metal-Oxide-Semiconductor Structure (*cont.*)

April 4, 2007

Contents:

1. Ideal MOS structure under bias (*cont.*)
2. Dynamics of the MOS structure

Reading assignment:

del Alamo, Ch. 8, §8.3 (8.3.5), §8.4 (8.4.1, 8.4.2)

Key questions

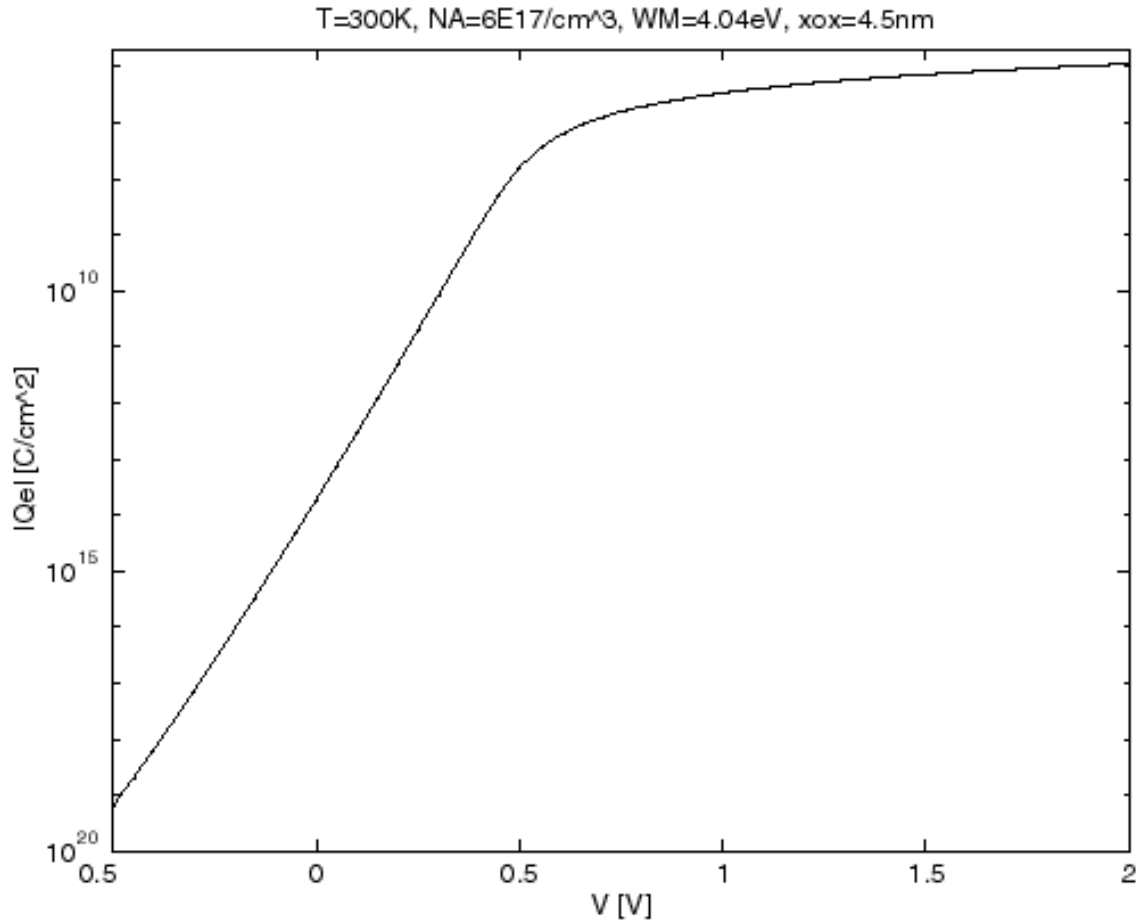
- How sharply does the inversion layer "turn on" and "off" with the gate voltage?
- How do the capacitance-voltage characteristics of the MOS structure look like?
- How do the C-V characteristics of a MOS structure depend on the frequency of the small signal?

1. MOS structure under bias (*cont.*)

□ Subthreshold regime

In MOSFETs interested in current with the device nominally OFF, that is, for $V < V_{th}$: SUBTHRESHOLD CURRENT

MOS structure in *depletion* but finite electron concentration at surface:

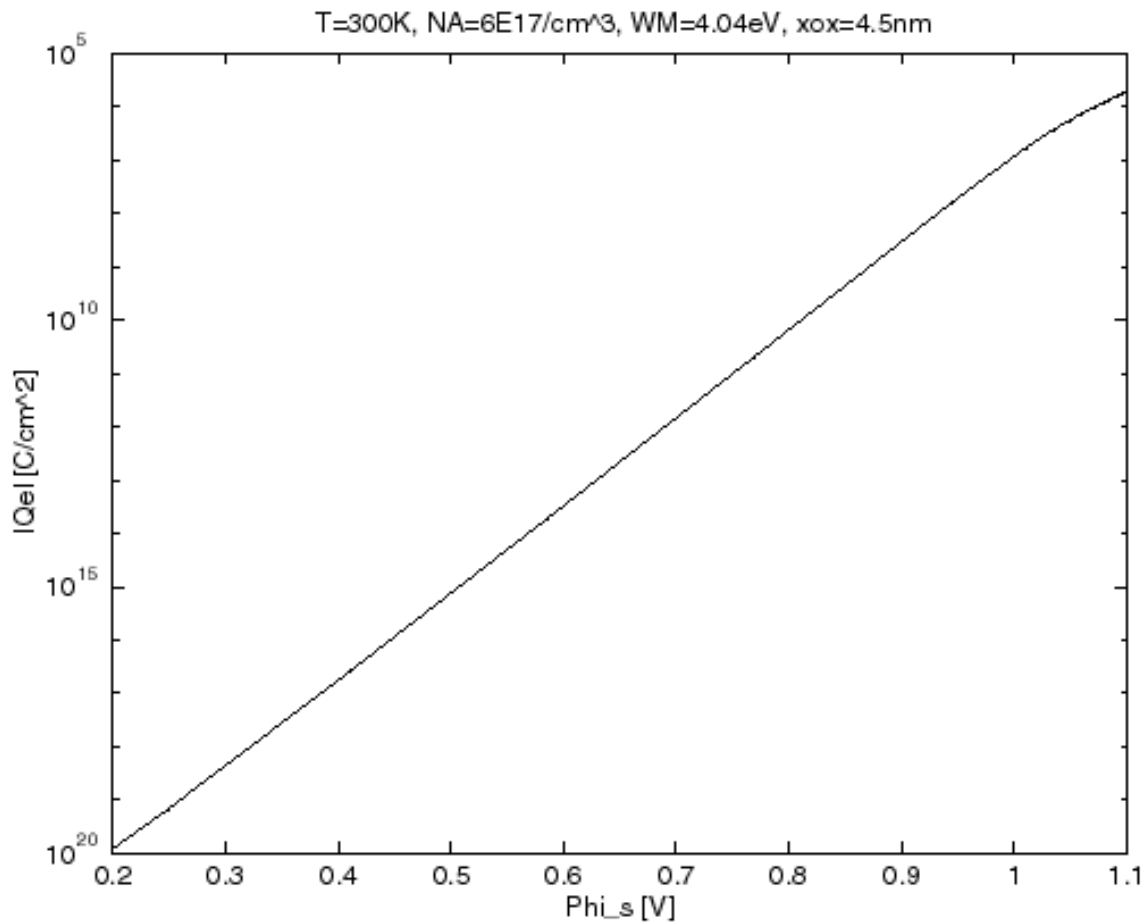


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Compute Q_e in depletion:

$$Q_e \simeq -\frac{kT}{q} \frac{n_i^2}{N_A^2} \sqrt{\frac{q\epsilon_s N_A}{2\phi_s}} \exp\left(\frac{q\phi_s}{kT}\right)$$

This key dependence seen in exact solution:



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Express Q_e in terms of V by expanding ϕ_s around ϕ_{sth} :

$$Q_e \simeq -\frac{kT}{q} \sqrt{\frac{q\epsilon_s N_A}{4\phi_f}} \exp\left(\frac{q(V - V_{th})}{nkT}\right)$$

with:

$$n = \left. \frac{dV}{d\phi_s} \right|_{th} \simeq 1 + \frac{\gamma}{2\sqrt{2}\phi_f}$$

Note:

$$n > 1$$

Key characteristic of subthreshold regime is *inverse subthreshold slope*:

$$S = n \frac{kT}{q} \ln 10$$

At best, if $n = 1$, $S = 60 \text{ mV/dec}$ at room temperature.

Typically, $S = 80 - 100 \text{ mV/dec}$.

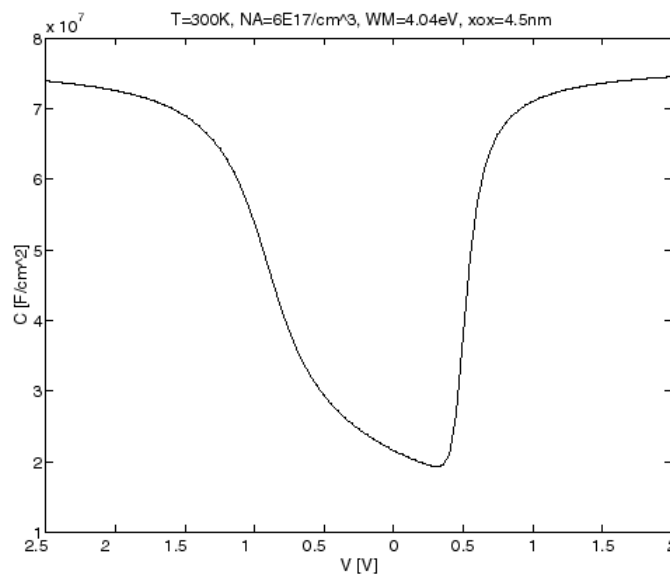
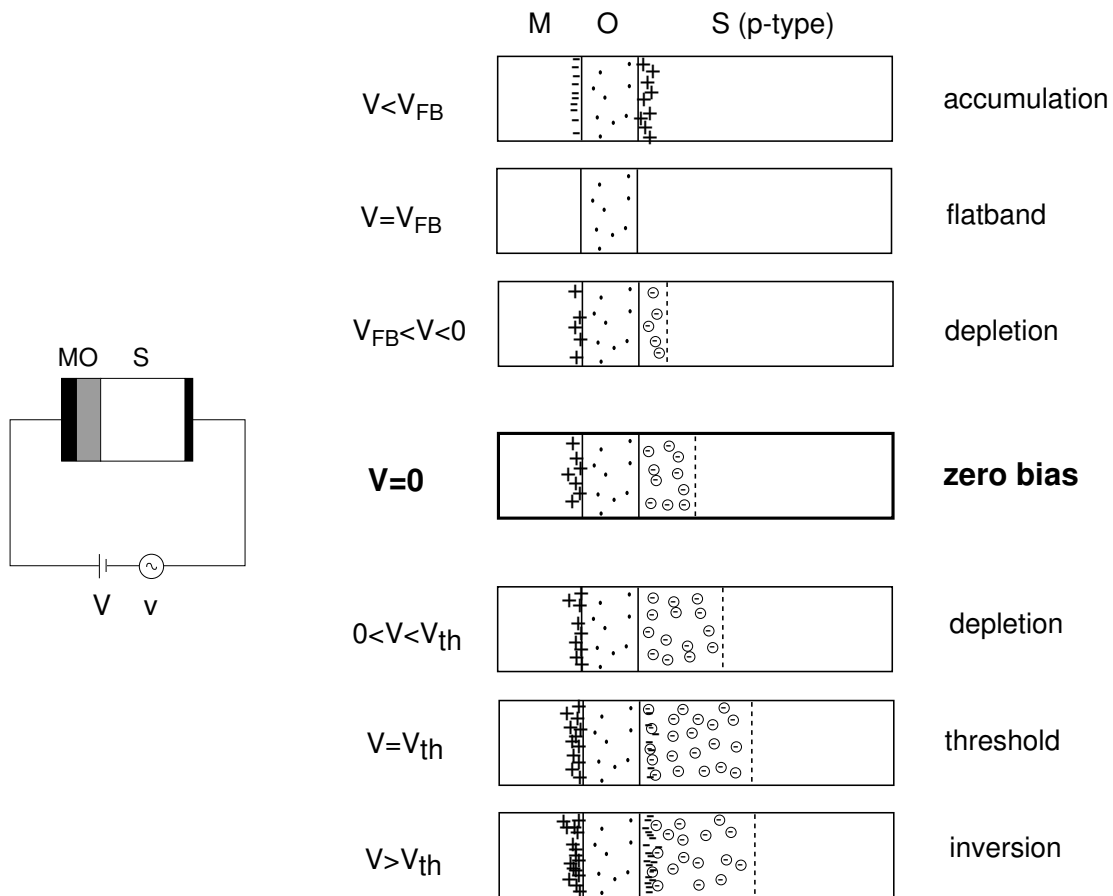
2. Dynamics of the MOS structure

- MOS structure looks and behaves like capacitor
- C-V characteristics summarize complex behavior of MOS
- C-V characteristics: powerful diagnostic tool of wide applicability

Three key issues to study:

- impact of bias voltage
- impact of frequency of small-signal
- dynamic behavior under fast changing conditions

□ Qualitative discussion first:



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□ General definition of capacitance:

$$C = \frac{dQ_g}{dV} = -\frac{dQ_s}{dV}$$

After some algebra:

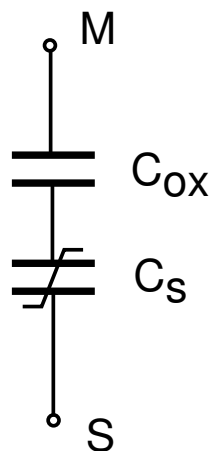
$$C = \frac{1}{\frac{1}{C_{ox}} + \frac{1}{C_s}}$$

where C_s is defined as:

$$C_s = -\frac{dQ_s}{d\phi_s}$$

Note: $C_s > 0$.

Simple physical interpretation:



□ Quasi-static C-V characteristics

If *frequency* of AC voltage signal is low enough: quasi-static conditions \Rightarrow use Poisson-Boltzmann formulation:

$$Q_s = -\sqrt{2\epsilon_s kT N_A} F(\phi_s)$$

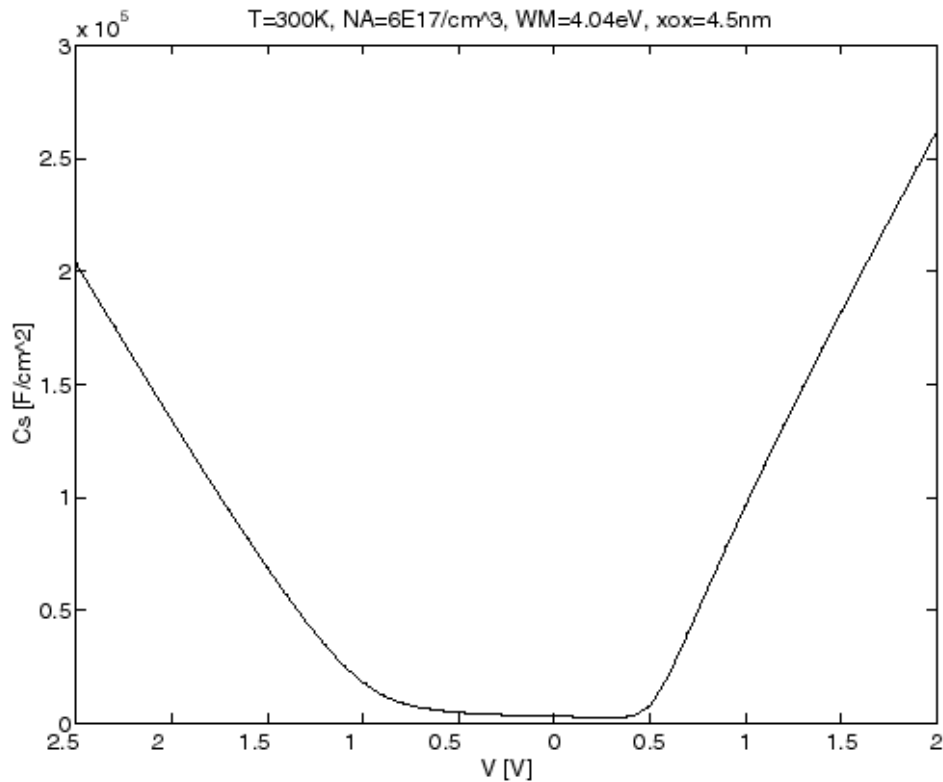
Then:

$$C_s = -\frac{dQ_s}{d\phi_s} = \sqrt{2\epsilon_s kT N_A} \frac{dF(\phi_s)}{d\phi_s}$$

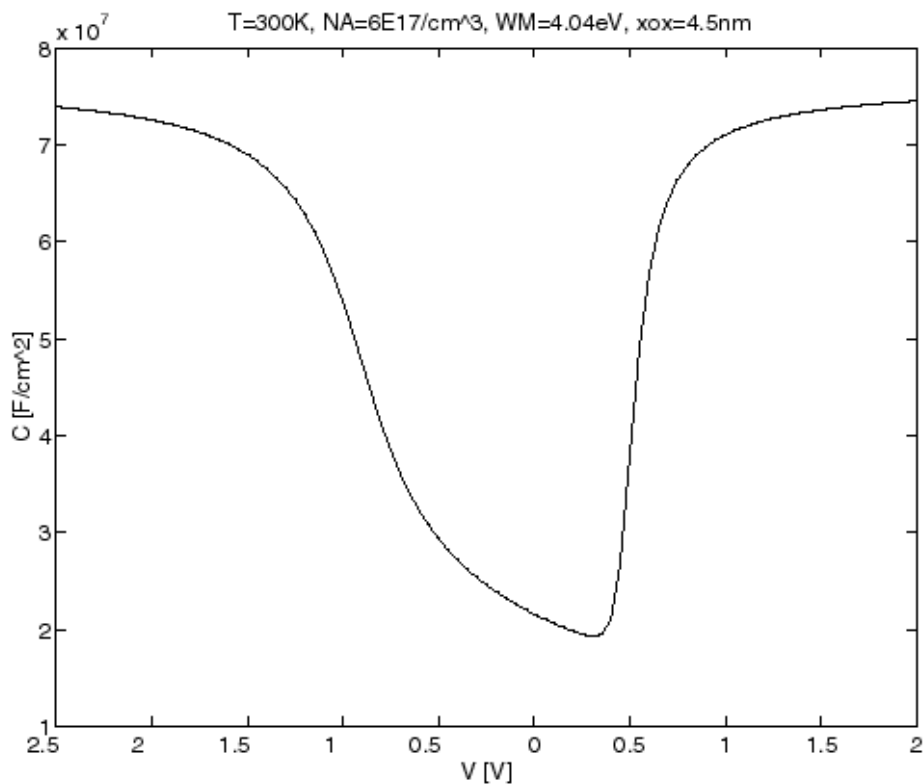
This yields:

$$C_s = \frac{\epsilon_s}{\sqrt{2}L_D} \frac{1}{F(\phi_s)} \left[\left(-\exp\left(\frac{-q\phi_s}{kT}\right) + 1 \right) + \frac{n_i^2}{N_A^2} \left(\exp\left(\frac{q\phi_s}{kT}\right) - 1 \right) \right]$$

Results of calculations for typical MOS structure:



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□ ANALYTICAL APPROXIMATIONS TO C • *Accumulation*

$$F(\phi_s) \simeq -\exp\left(\frac{-q\phi_s}{2kT}\right)$$

Then:

$$C_s \simeq \frac{q}{2kT} C_{ox} (V_{FB} - V)$$

For $|V|$ sufficiently larger than $|V_{FB}|$, C_s becomes large, and:

$$C \simeq C_{ox}$$

Independent of V .

- *Depletion*

$$F(\phi_s) \simeq \sqrt{\frac{q\phi_s}{kT}}$$

Which yields:

$$C_s \simeq \frac{C_{ox}}{\sqrt{1 + 4\frac{V-V_{FB}}{\gamma^2}} - 1}$$

Overall capacitance:

$$C \simeq \frac{C_{ox}}{\sqrt{1 + 4\frac{V-V_{FB}}{\gamma^2}}}$$

Square-root dependence on V .

- *Inversion*

$$F(\phi) \simeq \frac{n_i}{N_A} \exp \frac{q\phi}{2kT}$$

This results in:

$$C_s \simeq \frac{q}{2kT} C_{ox} (V - V_{th})$$

For V sufficiently larger than V_{th} , C_s is large and:

$$C \simeq C_{ox}$$

Independent of V .

□ High-frequency C-V characteristics

Time constants associated with charge modulation in semiconductor:

- *Accumulation*: hole concentration modulated in accumulation layer (majority carriers)

$$\tau \sim \max(\tau_d, RC)$$

- *Depletion*: hole concentration modulated at edge of depletion layer (majority carriers)

$$\tau \sim \max(\tau_d, RC)$$

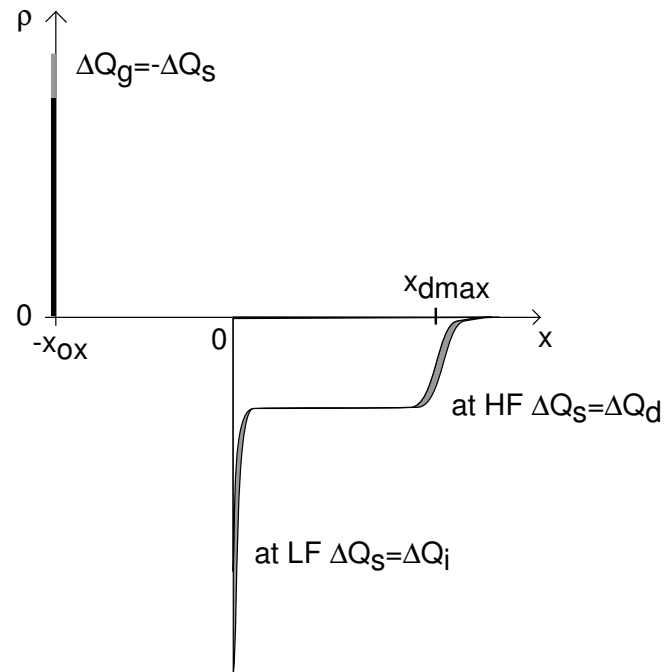
- *Inversion*: electron concentration modulated in inversion layer (minority carriers)

$$\tau \sim \tau_g$$

with $\tau_g \equiv$ generation lifetime.

For high-frequency AC signals, inversion layer can't keep up: C-V characteristics modified in inversion.

Evolution of ΔQ in inversion for LF and HF:



At low-frequency:

$$\Delta Q_s \simeq \Delta Q_i$$

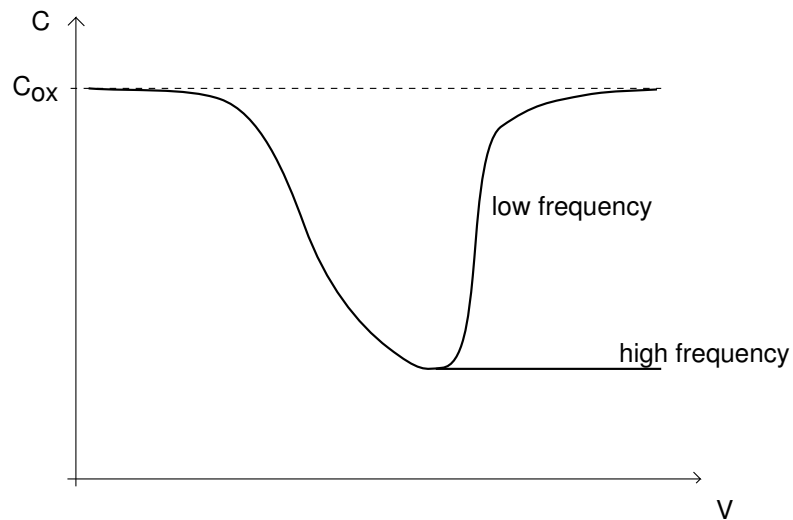
At high-frequency:

$$\Delta Q_s \simeq \Delta Q_d$$

Since $x_d \simeq x_{dmax}$,

$$C_{s,HF} \simeq C_{s,dep}(V_{th}) \simeq \frac{\gamma C_{ox}}{2\sqrt{2\phi_f}} \equiv C_{sth}$$

C-V characteristics:



Experimental high-frequency C-V characteristics:

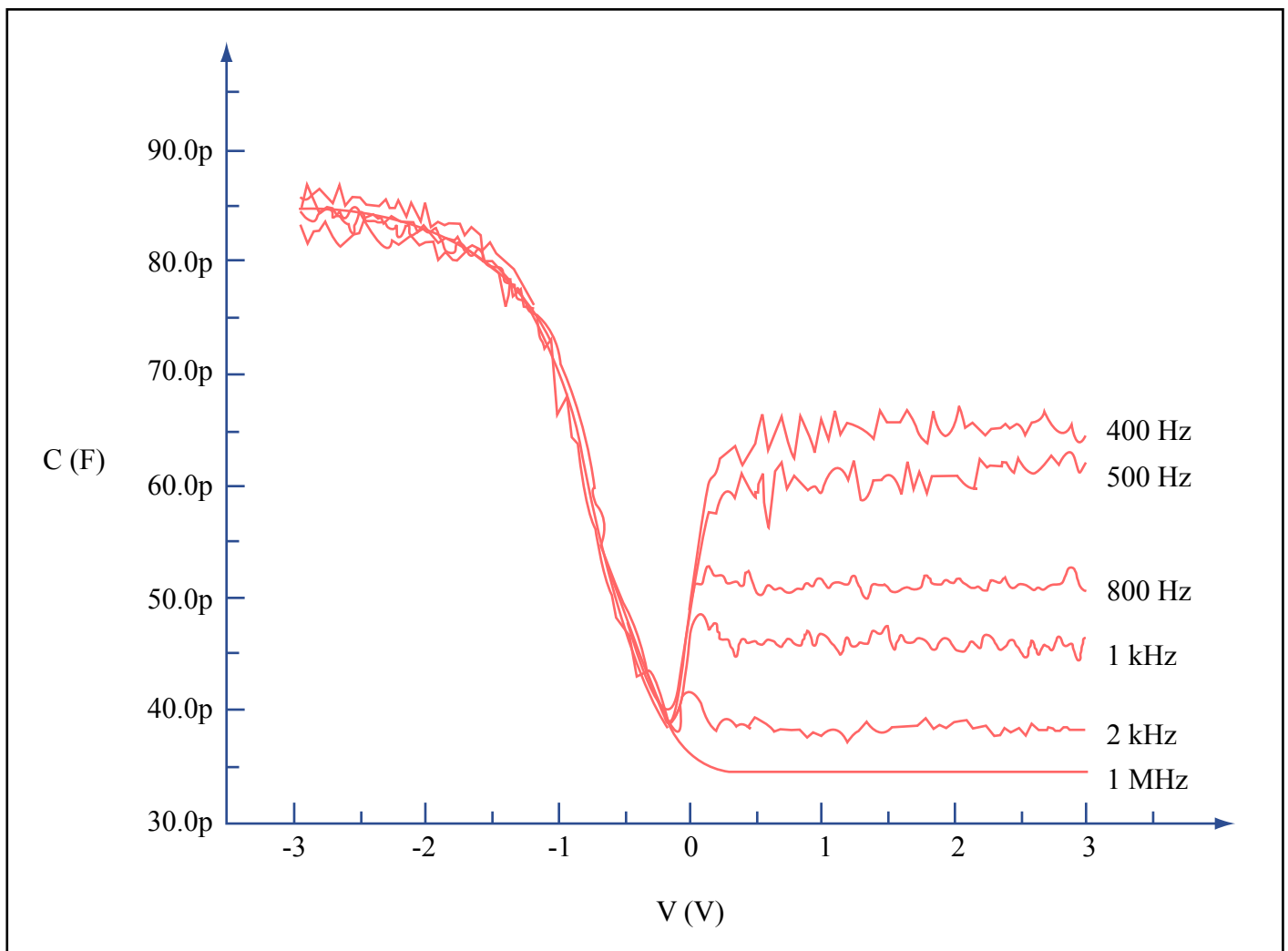


Image by MIT OpenCourseWare. Adapted from an image by Tassanee Payakapan, MIT.

Key conclusions

- In *subthreshold regime*, inversion charge drops exponentially with V below threshold:

$$Q_e \propto \exp \frac{q\phi_s}{kT} \propto \exp \frac{q(V - V_{th})}{nkT}$$

- *Inverse subthreshold slope*:

$$S = n \frac{kT}{q} \ln 10 \geq 60 \text{ mV/dec at } 300 \text{ K}$$

- Typical inverse subthreshold slope of well designed MOSFETs at 300 K: $S \sim 80 - 100 \text{ mV/dec}$.
- MOS capacitance: series of oxide capacitance and semiconductor capacitance:

$$\frac{1}{C} = \frac{1}{C_{ox}} + \frac{1}{C_s}$$

- For low-frequency excitation:

$$C(acc) \simeq C(inv) \simeq C_{ox}$$

Self study

- General derivation of C-V characteristics from Poisson-Boltzmann formulation.
- Algebra behind analytical approximations for capacitance-voltage characteristics in accumulation, depletion and inversion.